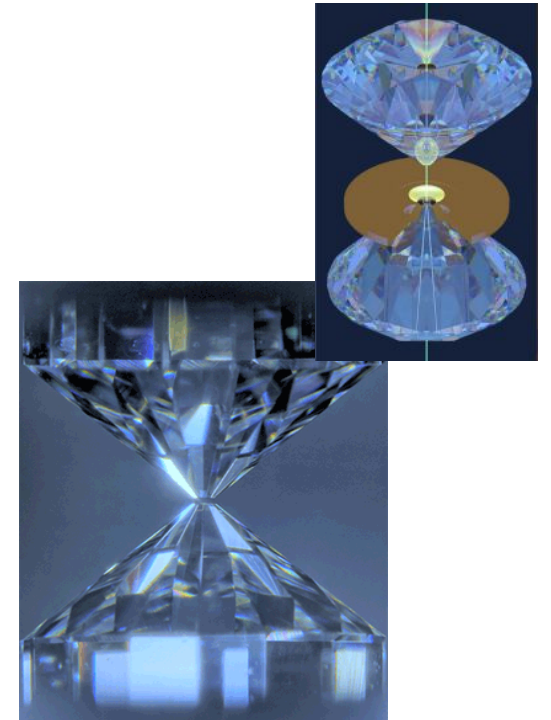


Lecture 4 – 01/10/2025

Strain effect on the band structure

- Introduction: strain, lattice-mismatch
- Elasticity theory



Summary Lecture 3

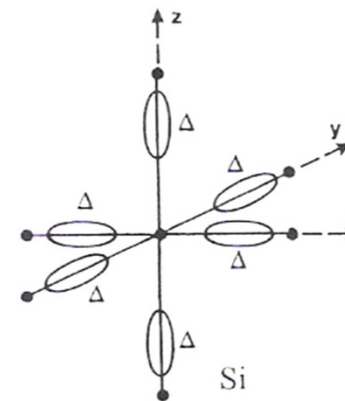
k.p method: Improvement over the nearly-free electron model. Able to predict the value of the band gap and effective masses but relies on experimental data

$$E_{c,k} = E_{c,0} + \frac{\hbar^2 k^2}{2m_0} \left(1 + \frac{P^2}{E_g} \right) = E_{c,0} + \frac{\hbar^2 k^2}{2m^*}$$

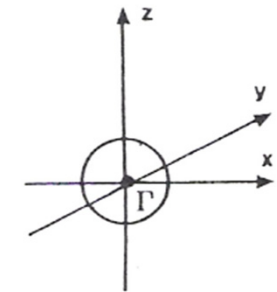
$$m^* = m_0 \left(1 + \frac{P^2}{E_g} \right)^{-1}$$

Effective mass: inversely proportional to the curvature of the k -space energy dispersion

- Direct band gap \Rightarrow conduction band is isotropic around $k = 0$
- Indirect band gap \Rightarrow conduction band is anisotropic



Anisotropic case



GaAs

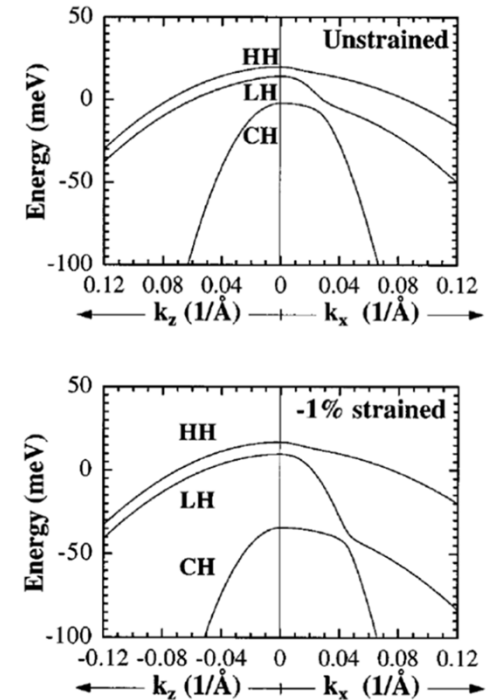
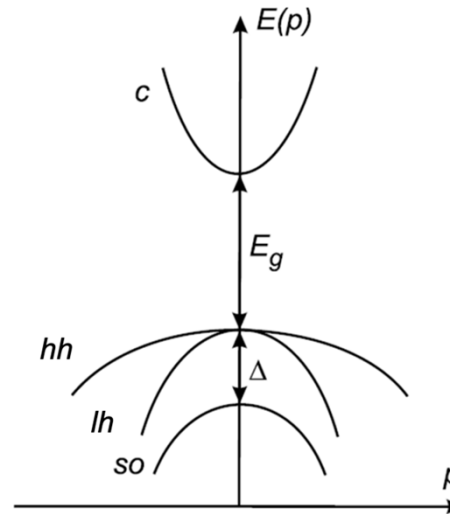
Isotropic case

Summary Lecture 3

In cubic semiconductors: The top of the valence band is split into heavy hole and light hole bands with $m_{hh} \gg m_{lh}$

Spin orbit valence band: It lies at a lower energy than the hh and lh valence subbands

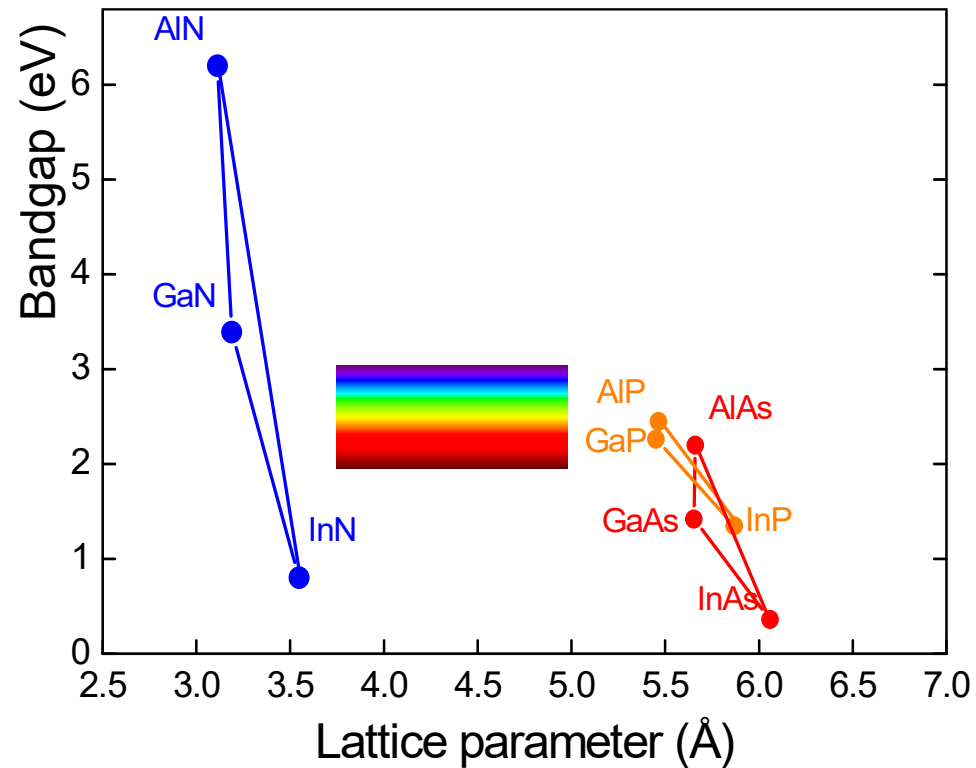
Δ is small for light atoms and large for heavy atoms. It can be as large as the band gap (e.g., InSb).



Strained semiconductors will exhibit a change in their band structure vs relaxed (unstrained) ones

Compound	AlAs	GaAs	InAs	AlP	GaP	InP	GaN
Δ_{so} (eV)	0.28	0.341	0.39	0.07	0.08	0.108	0.017

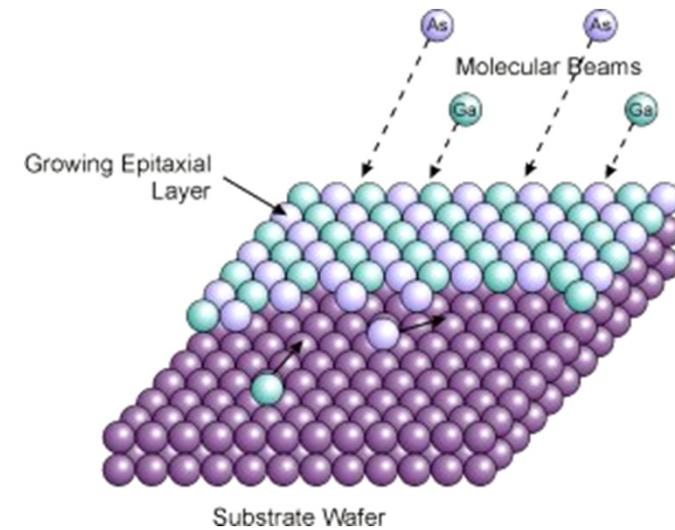
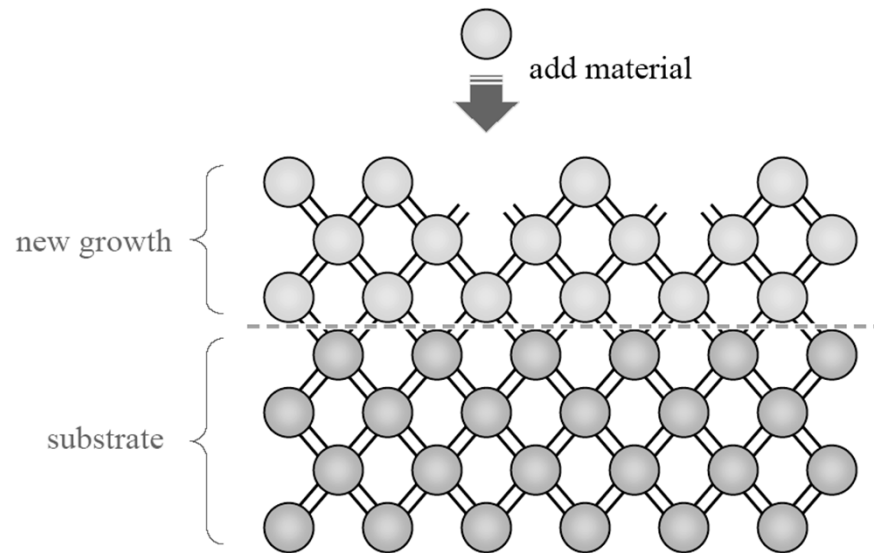
Lattice-mismatch in III-V semiconductors



The lattice parameters of semiconductors are almost never the same

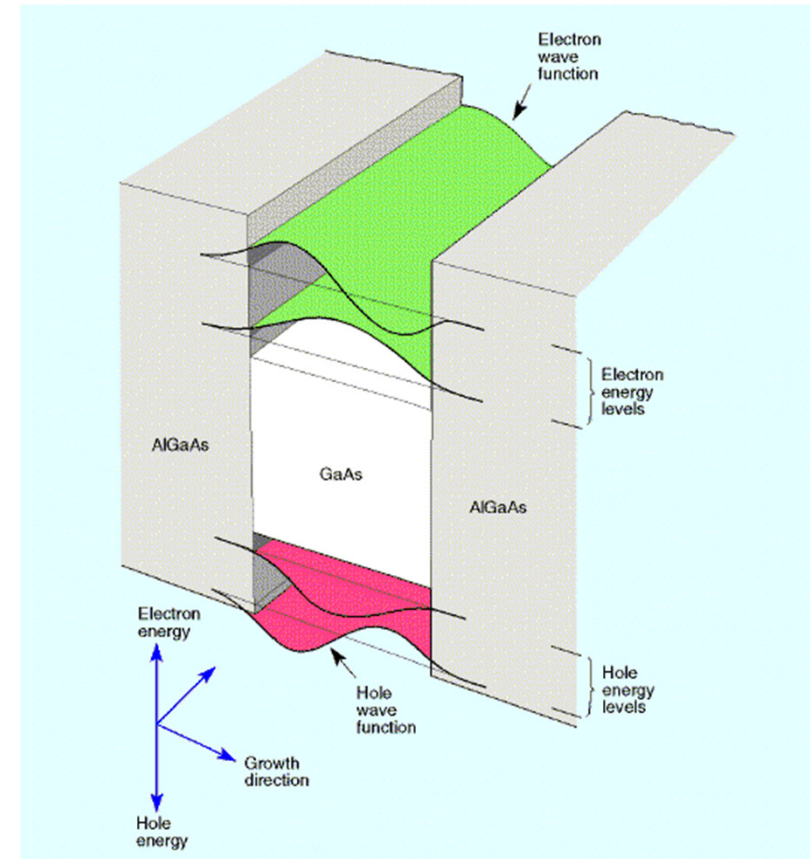
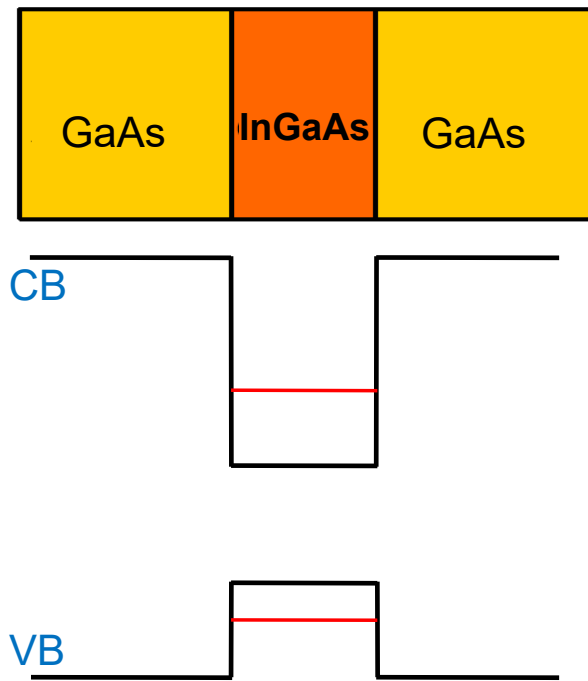
⇒ Strain induced in the semiconductor layers

Epitaxial growth



Epitaxy: crystal growth proceeds layer-by-layer and the layer structure complies with the substrate lattice

2D nanostructures: quantum wells

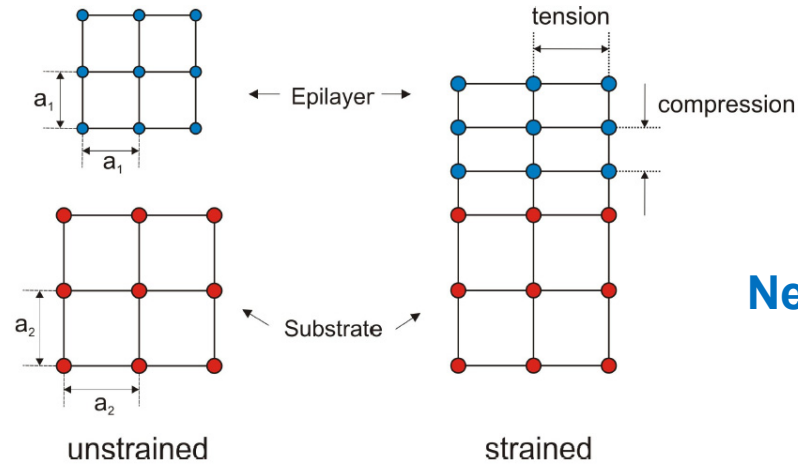
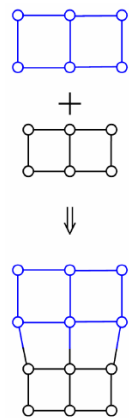
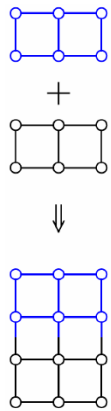


Epitaxial growth: case of heteroepitaxy

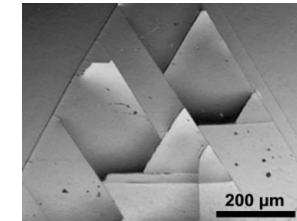
Epitaxial growth – Basic principle and problems

Lattice matched

Pseudomorphic

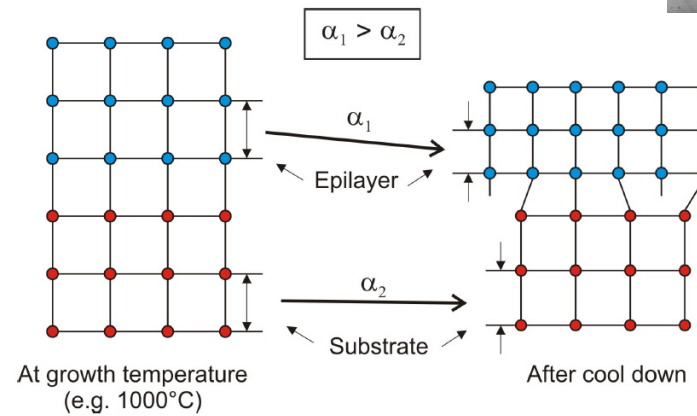


Network of cracks



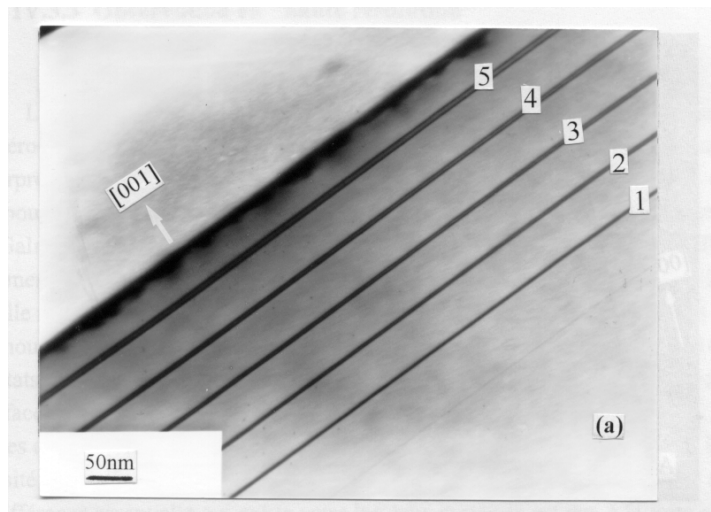
Thermal expansion coefficient (TEC), α

→ Different TECs lead to strain in the lattice



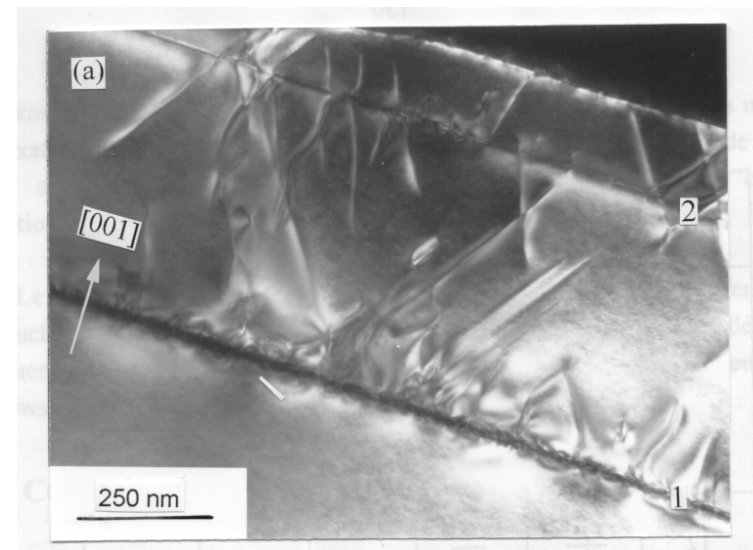
Heteroepitaxy: case of InGaAs/GaAs multiple quantum wells

No dislocation



Elastic deformation
(Coherent growth)

Dislocations

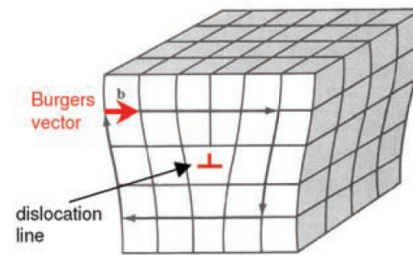
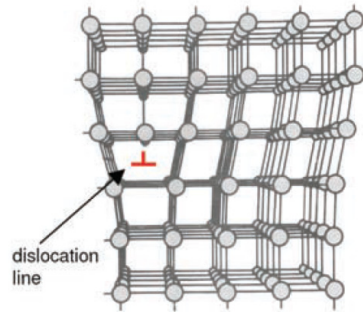


Plastic deformation

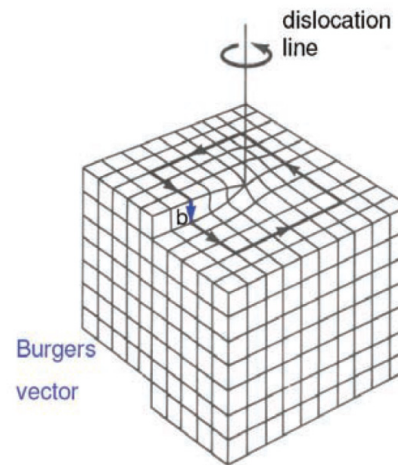
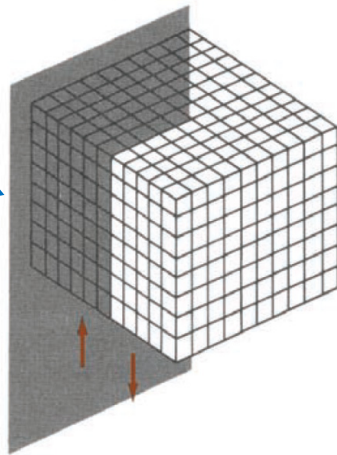
TEM

Extended defects: threading dislocations

Burgers vector \Rightarrow It represents the magnitude and direction of the lattice distortion caused by a dislocation in a crystal lattice



Gliding plane

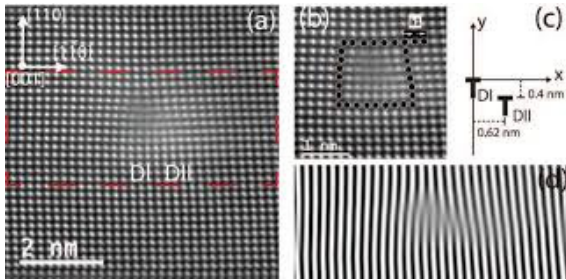


- **Edge type dislocation:**
The Burgers vector and the dislocation line are at right angles to one another

- **Screw type dislocation:**
The Burgers vector and the dislocation line are parallel

Dislocation usually associated with spiral growth

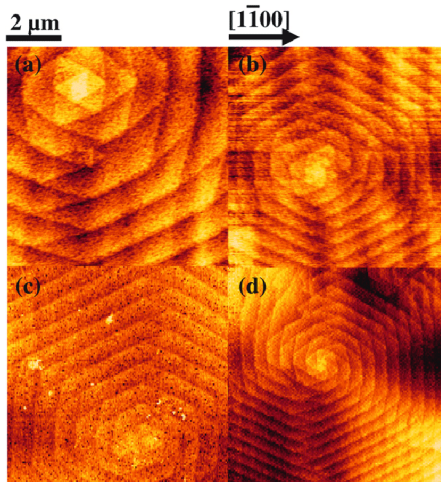
Imaging dislocations using microscopy techniques



Parallel edge threading dislocations in Ge crystals grown on Si (001) substrate

- **Edge type dislocation:**
The Burgers vector and the dislocation line are at right angles to one another

APL **107**, 093501 (2015)



N-face GaN (000-1)

- **Screw type dislocation:**
The Burgers vector and the dislocation line are parallel to one another
- Dislocation type usually associated with spiral growth

APEX **6**, 035503 (2013)

Critical thickness for plastic relaxation of a 2D layer

Minimizing the total energy density with respect to the dislocation line density yields the critical thickness h_c

h_c can be a macroscopic quantity ($> 1 \mu\text{m}$)!

$$h_c = \frac{Kb^2}{4\pi Bf_i b_{\parallel, \text{edge}}} \cdot \ln(h_c \alpha/b)$$

Transcendental equation!

b (b_{\parallel}): Burgers vector (edge component)

α : numerical factor accounting for the energy of the dislocation core

$B = 2\mu(1+\nu)/(1-\nu)$ Bulk modulus (infinitesimal pressure increase to relative volume decrease)

$K = \mu/(1-\nu)$ is the dislocation energy coefficient

f_i : misfit between substrate and growing layer

μ : shear modulus (pressure unit)

ν : Poisson's ratio (dimensionless parameter, usually > 0 , negative ratio of transverse to axial strain)

F. C. Frank and J. H. van der Merwe, Proc. R. Soc. London, Ser. A **198**, 205 (1949); [> 1600 citations](#)

J. H. van der Merwe, Crit. Rev. Solid State Mater. Sci. **17**, 187 (1991).

Strain and heteroepitaxy

Lattice-mismatch: $\Delta a/a = (a_l - a_s)/a_s$

a_s : in-plane lattice parameter of the *substrate*

(In-plane) strain: $\varepsilon_{//} = (a_s - a_l)/a_l$

a_l : relaxed value of the in-plane lattice parameter of the *deposited layer*

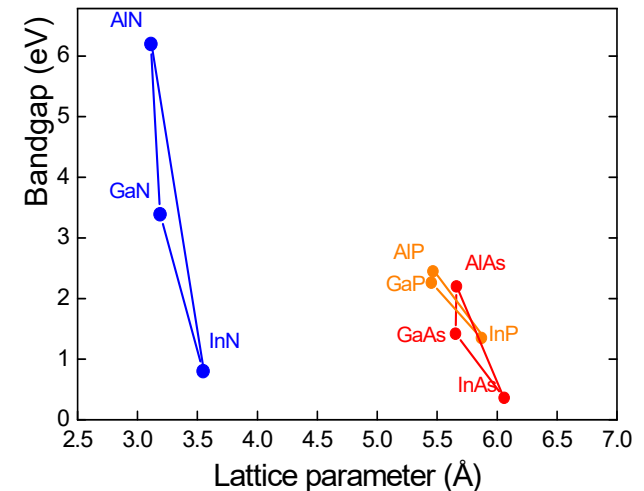
Example: AlN/GaN combination

$a_{\text{GaN}} = 3.189 \text{ \AA}$ and $a_{\text{AlN}} = 3.112 \text{ \AA}$

GaN on AlN: $\Delta a/a = 2.47\%$ and $\varepsilon_{//} = -2.42\%$

$\varepsilon_{//} < 0$ compressive strain

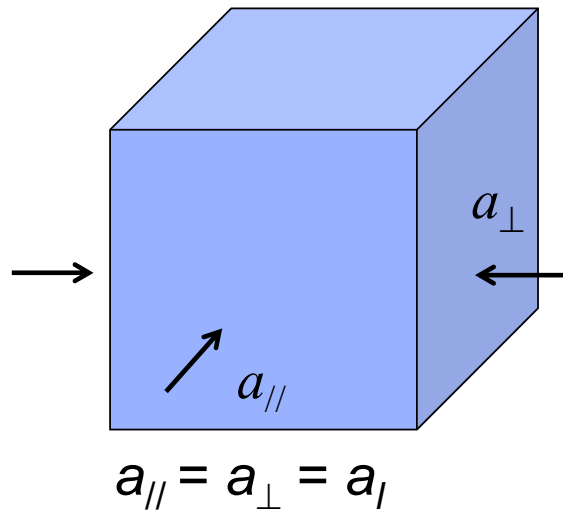
$\varepsilon_{//} > 0$ tensile strain



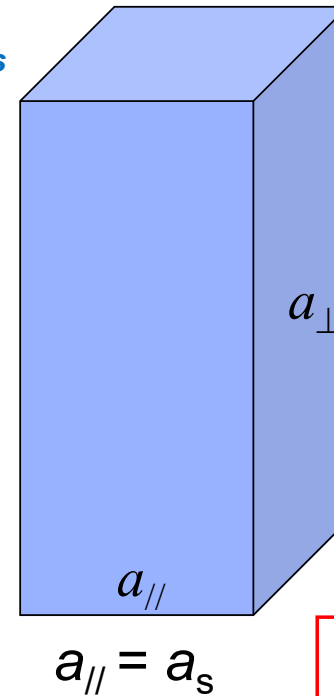
Biaxial strain (compression)

Growth on a substrate with lattice parameter a_s

Unstrained case



Strained case



$$\varepsilon_{||} = (a_s - a_l) / a_l$$

Deformation at the level of a single monolayer!

$$a_{\perp} = (1 + \varepsilon_{\perp}) a_l$$

Out of plane strain

h_c linked to the lattice deformation along the growth axis a_{\perp}

\Rightarrow necessity to determine ε_{\perp} to deduce the growth time or the number of monolayers before plastic relaxation occurs $\Rightarrow h_c$ should be an "integer" multiple of a_{\perp}

Elasticity theory

Elastic deformation:

Hooke's law: relation between the tensors of **deformations** ε_{ij} , **stress** σ_{ij} , and **elastic constants**

C_{ijkl} : $\sigma_{kl} = C_{ijkl} \varepsilon_{ij}$ (use of Einstein summation notation (i.e., summation takes place when an index variable appears twice in a single term))

dimensionless

\equiv pressure

For cubic crystals defined by the crystallographic axes [100], [010] and [001]:

$$\begin{pmatrix} \sigma_1 \\ \sigma_2 \\ \sigma_3 \\ \sigma_4 \\ \sigma_5 \\ \sigma_6 \end{pmatrix} = \begin{pmatrix} C_{11} & C_{12} & C_{12} & 0 & 0 & 0 \\ C_{12} & C_{11} & C_{12} & 0 & 0 & 0 \\ C_{12} & C_{12} & C_{11} & 0 & 0 & 0 \\ 0 & 0 & 0 & C_{44} & 0 & 0 \\ 0 & 0 & 0 & 0 & C_{44} & 0 \\ 0 & 0 & 0 & 0 & 0 & C_{44} \end{pmatrix} \times \begin{pmatrix} \varepsilon_1 \\ \varepsilon_2 \\ \varepsilon_3 \\ \varepsilon_4 \\ \varepsilon_5 \\ \varepsilon_6 \end{pmatrix}$$

Overview

Elasticity theory

A few words on Voigt notations:

Indices: $\sigma_1 = \sigma_{xx} = \sigma_{11}$, equivalently 2 = y and 3 = z

$\sigma_4 = \sigma_{yz}$, $\sigma_5 = \sigma_{zx}$ and $\sigma_6 = \sigma_{xy}$

The same statement for indices holds for the components of the tensor of deformations $\varepsilon_i = 1$ to 6

Elasticity theory

During growth, the surface is stress-free and can freely move along the growth axis (usually coinciding with z). Thus, it leads to:

$$\sigma_{13} = 0$$

$$\sigma_{23} = 0$$

$$\sigma_{33} = 0$$

Extra note: The boundary conditions are such that this type of epilayer (i.e., a 2D layer heteroepitaxially grown on a substrate) undergoes zero stress in the z direction, zero shear stresses, and it has in-plane symmetry of x and y directions.

In the layer plane, the deformations are identical:

$$\varepsilon_{11} = \varepsilon_{22} = \varepsilon_{//}$$

$$\varepsilon_{12} = 0$$

Let us write (cf. slide 13) $\varepsilon_{\perp} = \varepsilon_{33}$ and $\varepsilon_{//} = (a_{\parallel} - a_{\parallel}^0) / a_{\parallel}^0$ ← Relaxed value of the in-plane lattice parameter

Elasticity theory: case of an epitaxial growth system

$[hkl] = [001]$: Orientation at play for the CMOS technology (but not only)!

$$\varepsilon_{13} = 0$$

$$\sigma_{11} = \sigma_{22} = \varepsilon_{//} (C_{11} + 2C_{12})(C_{11} - C_{12}) / C_{11}$$

$$\varepsilon_{\perp} = -2 C_{12} / C_{11} \varepsilon_{//}$$

Relationship deduced from Hooke's law: a tensile in-plane strain leads to a compressive out-of-plane deformation and vice versa!

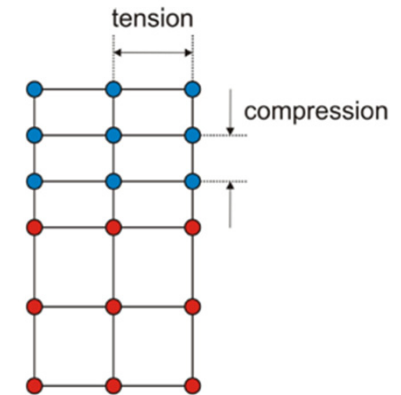
$[hkl] = [111]$:

Cf. sketch on top of slide 7!

$$\varepsilon_{13} = 0$$

$$\sigma_{11} = \sigma_{22} = \varepsilon_{//} 6C_{44}(C_{11} + 2C_{12}) / (C_{11} + 2C_{12} + 4C_{44})$$

$$\varepsilon_{\perp} = -2 (C_{11} + 2C_{12} - 2C_{44}) / (C_{11} + 2C_{12} + 4C_{44}) \varepsilon_{//}$$



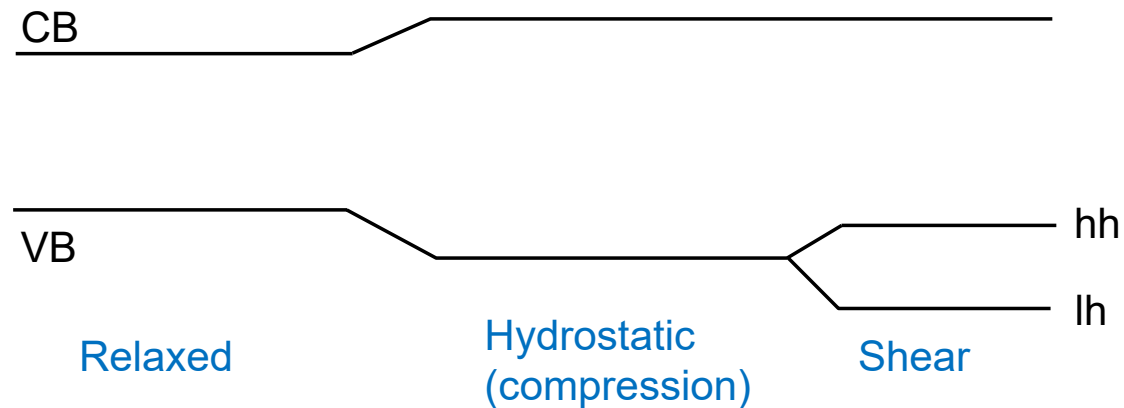
ε and σ can be calculated provided C_{ij} are known (accessible via Raman spectroscopy)

Strain effect on the band structure

The crystal symmetry is changed and thereby the band structure

The strain Hamiltonian can be written as the sum of two components: a purely hydrostatic term H_H and a shear strain term H_S .

$$H = H_H + H_S$$

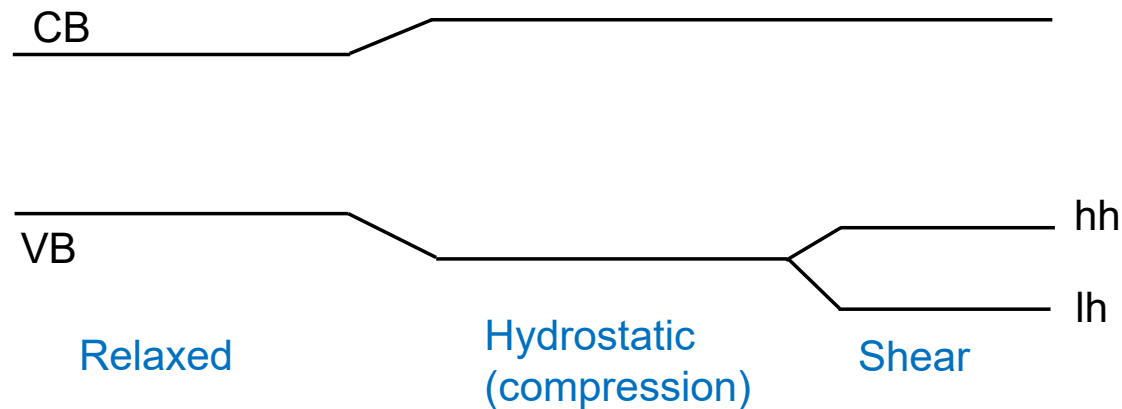


Case of a cubic semiconductor

Strain effect on the band structure

The band structure is affected in different ways by deformations:

1. A volume dilatation (described by LA-phonons at the microscopic scale) does not change the crystal symmetry but the e-LA phonon interaction is responsible for a change in bandgap (e.g., an increase for hydrostatic pressure)
2. TA-phonons contain shear waves (*shear component LA-phonons less important*) \Rightarrow shear strain:
 - (i) does not affect (to 1st order) the energy of a nondegenerate band in a cubic crystal,
 - (ii) does lift some of the degeneracy of energy bands at high-symmetry points of the 1st Brillouin zone (*Matrix-element theorem + crystal symmetry*)



Cf. Chap. 3
Yu-Cardona

Strain effect on the band structure

$$\Sigma_H = 2 (1 - C_{12}/C_{11}) \epsilon_{//} \quad \text{Hydrostatic deformation}$$

$$\Sigma_S = -2 (1 + 2C_{12}/C_{11}) \epsilon_{//} \quad \text{Shear deformation}$$

Cubic semiconductor

"Hydrostatic" term

1. Conduction band

Due to symmetry reasons, only the hydrostatic component plays a role on the CB and E_C changes by $\delta E_C = a_c \Sigma_H$ where a_c is the CB potential of deformation

Dimensionality: energy

2. Valence band

The hydrostatic component modifies the VB edge E_V by $\delta E_V = a_v \Sigma_H$ where a_v is the VB potential of deformation

Strain effect on the band structure

“Shear” term

The shear strain deeply affects the ordering of the valence band levels (hh, lh, and spin-orbit). Given b_v the potential of deformation due to shear strain and Δ_{SO} the spin-orbit splitting, the energy shifts of hh and lh write

$$\delta E_{hh} = -b_v \Sigma_s$$

$$\delta E_{lh} = -\frac{\Delta_{SO} - b_v \Sigma_s - \sqrt{(\Delta_{SO} + b_v \Sigma_s)^2 + 8(b_v \Sigma_s)^2}}{2}$$

Case of zinc-blende SCs

In summary, we have (at the Γ -point):

$$E_e = E_v + E_g + a_c \Sigma_H$$

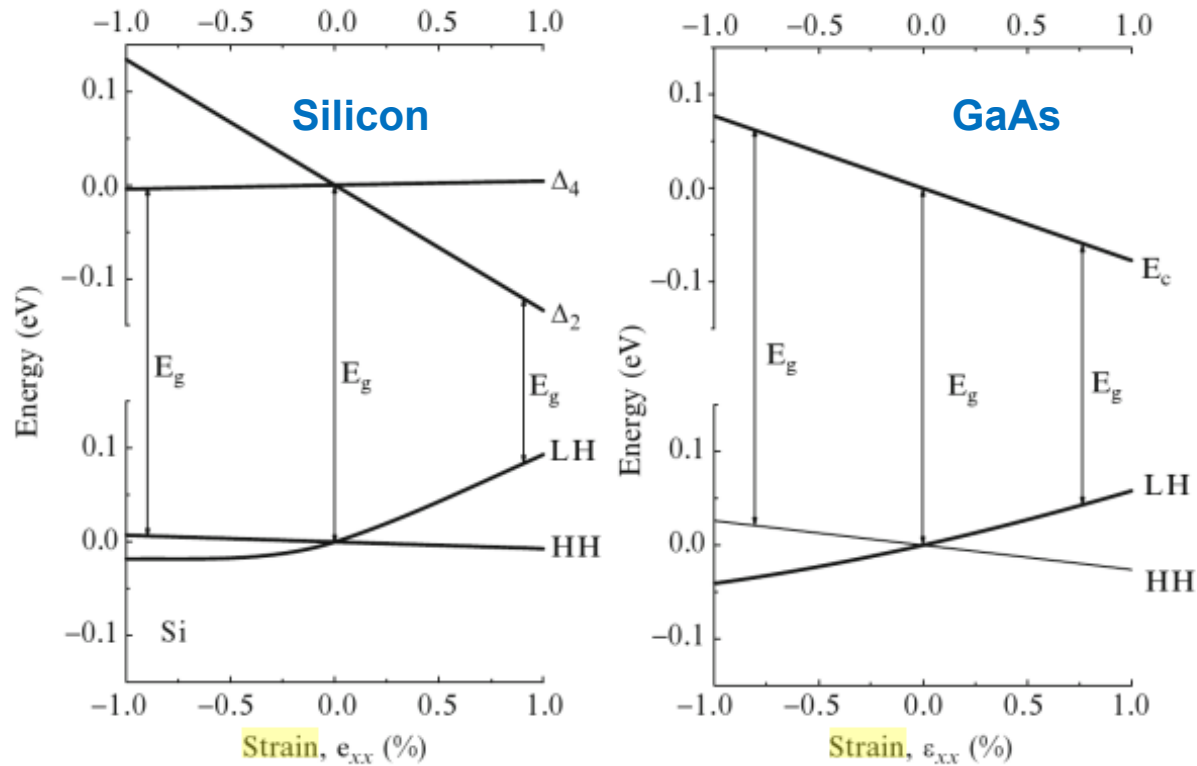
$$E_{hh} = E_v + a_v \Sigma_H - b_v \Sigma_s$$

$$E_{lh} = E_v + a_v \Sigma_H - \frac{\Delta_{SO} - b_v \Sigma_s - \sqrt{(\Delta_{SO} + b_v \Sigma_s)^2 + 8(b_v \Sigma_s)^2}}{2}$$

Numerical example using the band structure parameters of GaAs

Δ_{SO} (eV)	C_{11} (GPa)	C_{12} (GPa)	a_c (eV)	a_v (eV)	b_v (eV)
0.341	1221	566	-7.17	1.16	-2.0

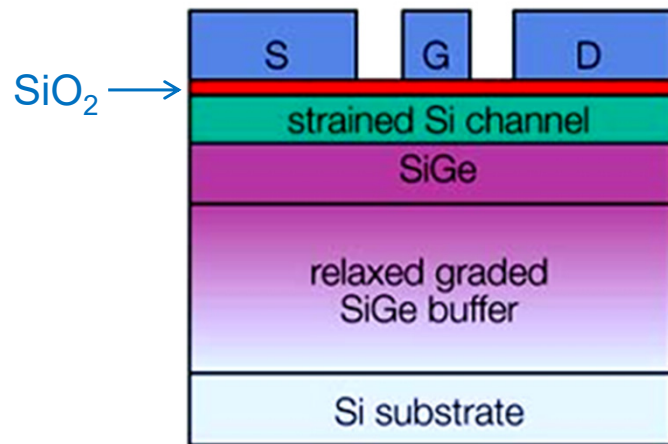
Strain effect on the band structure



Strain Effect in Semiconductors: Theory and Device Applications

Yongke Sun, Scott Thompson, Toshikazu Nishida

Si/SiGe MOSFET



(a) surface-channel MOSFET

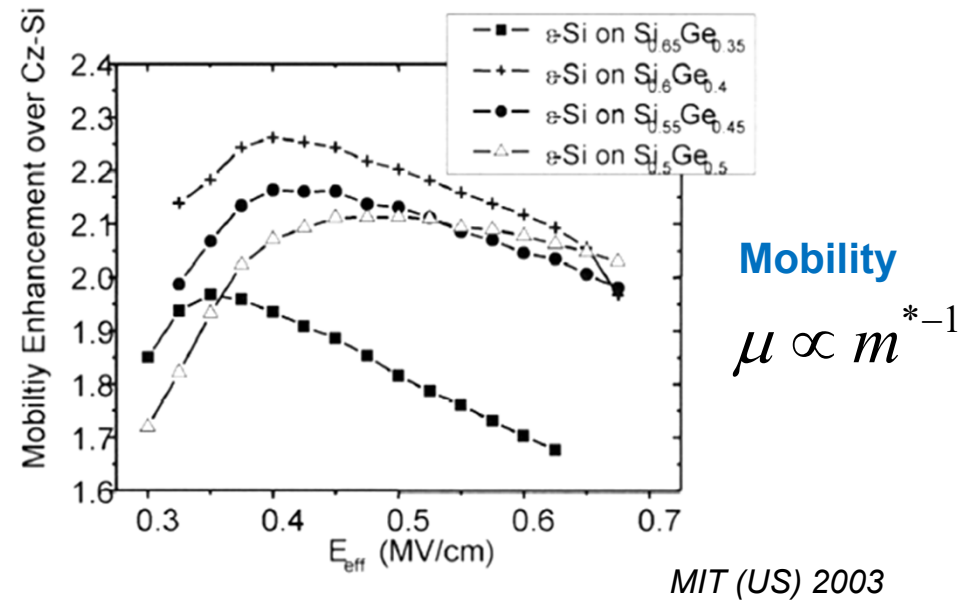
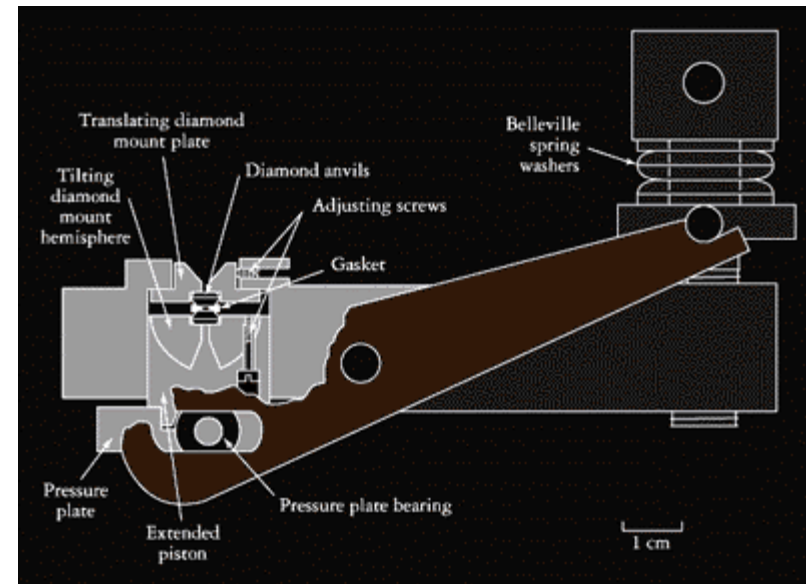
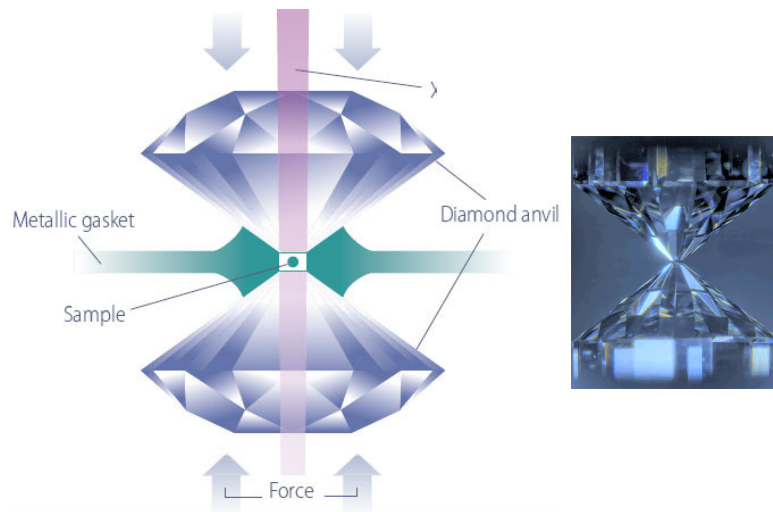


Figure 1. The mobility enhancement of holes vs. vertical field under the gate in PMOSFETs in strained Si for different Ge concentrations in the relaxed $\text{Si}_{1-x}\text{Ge}_x$ buffer.

Origin of this MOSFET transistor performance enhancement?

Strain effect on the band structure

- **Hydrostatic strain**
 - Equivalent strain along x, y, and z



- **Biaxial strain**
 - Strain along 2 directions: strained semiconductor epilayers